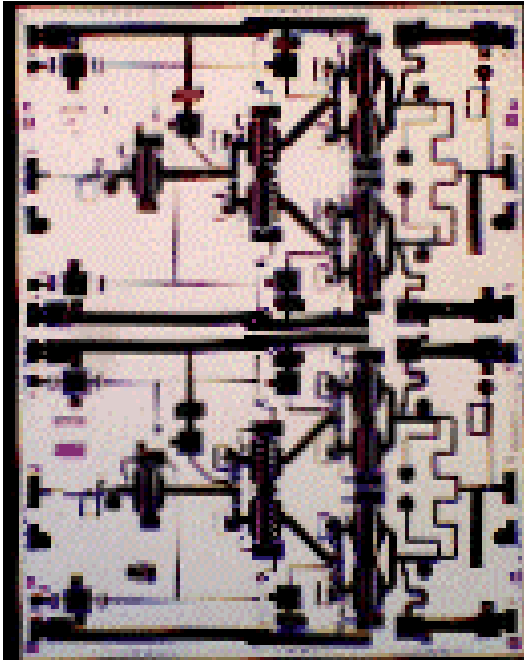


6 - 18 GHz High Power Amplifier

TGA9092-SCC



Chip Dimensions 5.739 mm x 4.318 mm x 0.1016 mm

Product Description

The TriQuint TGA9092-SCC is a dual channel, three-stage wide band HPA MMIC designed using TriQuint's proven 0.25 μ m Power pHEMT process to support a variety of high performance applications including military EW programs, VSAT, and other applications requiring wideband high power performance.

Each amplifier channel consists of one 1200 μ m input device driving a 2400 μ m intermediate stage which drives a 4800 μ m output stage.

The TGA9092-SCC provides a nominal 34 dBm of output power at 2dB gain compression across the 6-18 GHz range per channel . Power combined, nominal output power of 36.5 dBm can be expected with low loss external couplers. Typical per channel small signal gain is 24 dB. Typical single-ended Input/Output RL is 6-8 dB across the band.

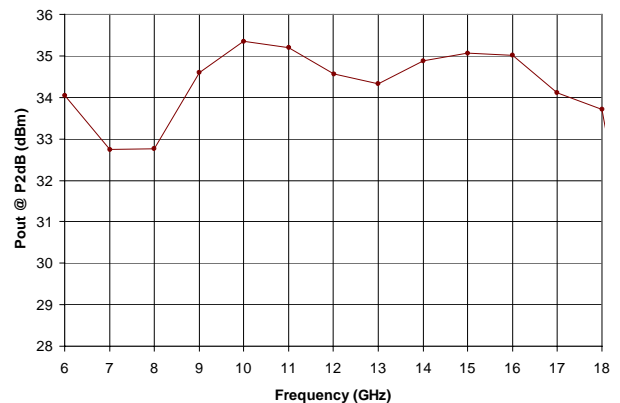
The TGA9092-SCC is 100% DC and RF tested on-wafer to ensure performance compliance. The device is available in chip form.

Key Features and Performance

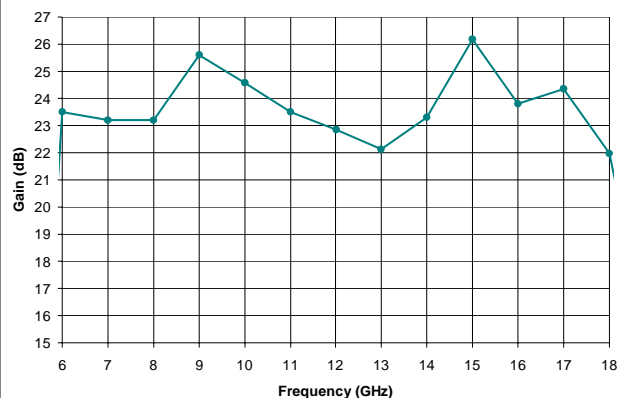
- Dual Channel Power Amplifier
- 0.25 μ m pHEMT Technology
- 6-18 GHz Frequency Range
- 2.8 W/Channel Midband Pout
- 5.6 W Pout Combined
- 24 dB Nominal Gain
- Balanced In/Out for Low VSWR
- 8V @ 1.2A per Channel Bias

Primary Applications

- X-Ku band High Power
- VSAT



Typical Measured Pout (RF Probe)



Typical Measured Small Signal Gain

TABLE I
MAXIMUM RATINGS

Symbol	Parameter <u>5/</u>	Value	Notes
V ⁺	Positive Supply Voltage	9 V	<u>4/</u>
V ⁻	Negative Supply Voltage Range	-5V TO 0V	
I ⁺	Positive Supply Current (Quiescent)	3.5 A	<u>4/</u>
I _G	Gate Supply Current	84.48 mA	
P _{IN}	Input Continuous Wave Power	26 dBm	<u>4/</u>
P _D	Power Dissipation	28.8 W	<u>3/ 4/</u>
T _{CH}	Operating Channel Temperature	150 °C	<u>1/ 2/</u>
T _M	Mounting Temperature (30 Seconds)	320 °C	
T _{STG}	Storage Temperature	-65 to 150 °C	

- 1/ These ratings apply to each individual FET.
- 2/ Junction operating temperature will directly affect the device median time to failure (T_M). For maximum life, it is recommended that junction temperatures be maintained at the lowest possible levels.
- 3/ When operated at this bias condition with a base plate temperature of 70 °C, the median life is reduced from 1.6 E+6 to 5.4 E+4 hours.
- 4/ Combinations of supply voltage, supply current, input power, and output power shall not exceed P_D.
- 5/ These ratings represent the maximum operable values for this two-channel device.

TABLE II
DC PROBE TEST
(TA = 25 °C ± 5 °C)

Symbol	Parameter	Minimum	Maximum	Unit
I _{max(Q1)}	Maximum Current	400	800	mA
G _{m (Q1)}	Transconductance	200	600	mS
V _P	Pinch-off Voltage	-1.5	-0.5	V
BVGS	Breakdown Voltage Gate-Source	-30	-13	V
BVGD	Breakdown Voltage Gate-Drain	-30	-13	V

TABLE III
AUTOPROBE FET PARAMETER MEASUREMENT CONDITONS

FET Parameters	Test Conditions
G _m : Transconductance; $\frac{(I_{DSS} - I_{DS1})}{V_{G1}}$	For all material types, V _{DS} is swept between 0.5 V and VDSP in search of the maximum value of I _{ds} . This maximum I _{DS} is recorded as IDS1. For Intermediate and Power material, IDS1 is measured at V _{GS} = V _{G1} = -0.5 V. For Low Noise, HFET and pHEMT material, V _{GS} = V _{G1} = -0.25 V. For LNBECOLC, use V _{GS} = V _{G1} = -0.10 V.
V _P : Pinch-Off Voltage; V _{GS} for I _{DS} = 0.5 mA/mm of gate width.	V _{DS} fixed at 2.0 V, V _{GS} is swept to bring I _{DS} to 0.5 mA/mm.
V _{BVGD} : Breakdown Voltage, Gate-to-Drain; gate-to-drain breakdown current (I _{BD}) = 1.0 mA/mm of gate width.	Drain fixed at ground, source not connected (floating), 1.0 mA/mm forced into gate, gate-to-drain voltage (V _{GD}) measured is V _{BDGD} and recorded as BVGD; this cannot be measured if there are other DC connections between gate-drain, gate-source or drain-source.
V _{BVGS} : Breakdown Voltage, Gate-to-Source; gate-to-source breakdown current (I _{BS}) = 1.0 mA/mm of gate width.	Source fixed at ground, drain not connected (floating), 1.0 mA/mm forced into gate, gate-to-source voltage (V _{GS}) measured is V _{BDGS} and recorded as BVGS; this cannot be measured if there are other DC connections between gate-drain, gate-source or drain-source.
I _{MAX} : Maximum I _{DS} .	Positive voltage is applied to the gate to saturate the device. V _{DS} is stepped between 0.5 V up to a maximum of 3.5 V, searching for the maximum value of I _{DS} .

TABLE IV
RF WAFER CHARACTERIZATION TEST*
($T_A = 25^\circ\text{C} \pm 5^\circ\text{C}$)
($V_d = 8\text{V}$, $I_d = 1.2\text{A} \pm 5\%$)

Parameter	Test Condition	Limit			Units
		Min	Nom	Max	
Small-signal Power Gain	F = 6 to 17 GHz F = 18 GHz	20 18	24	-	dB
Input Return Loss	F = 6 to 18 GHz		6		dB
Output Return Loss	F = 6 to 18 GHz		8		dB
Output Power @ 2dB gain compression	F = 6 to 8 GHz F = 9 to 18 GHz	32 32.5	34.5	- -	dBm
Power Added Efficiency	F = 6 to 18 GHz	12	25	-	%

Note: RF probe data taken at 1 GHz steps

* This information is based on the per-channel device.

TABLE V
THERMAL INFORMATION*

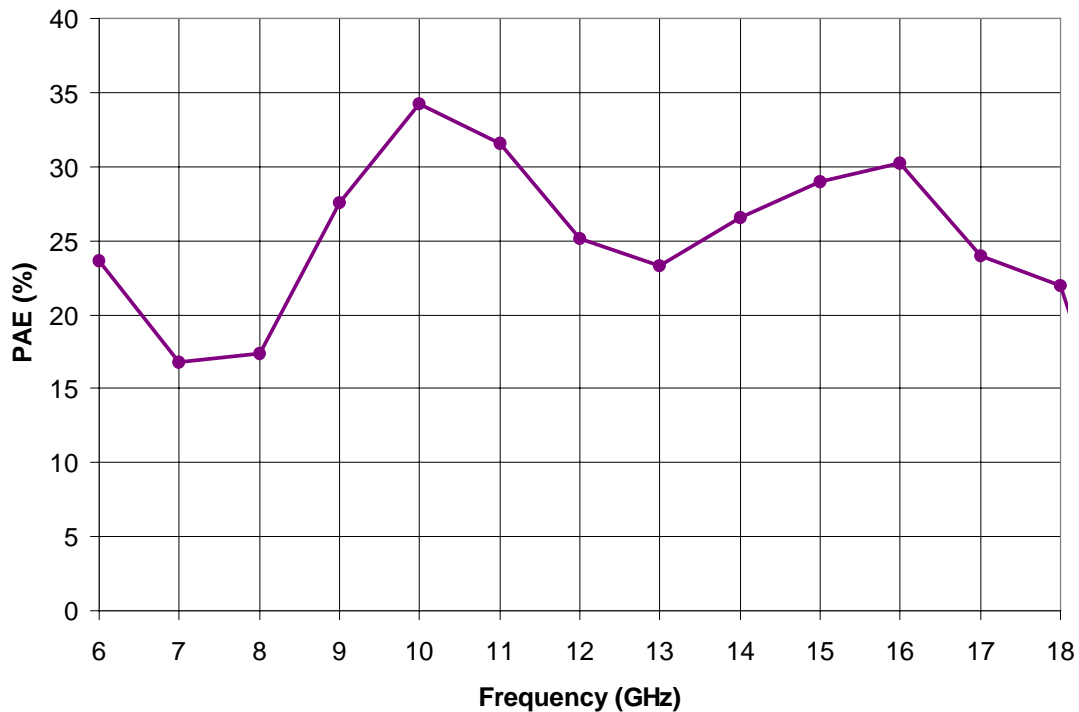
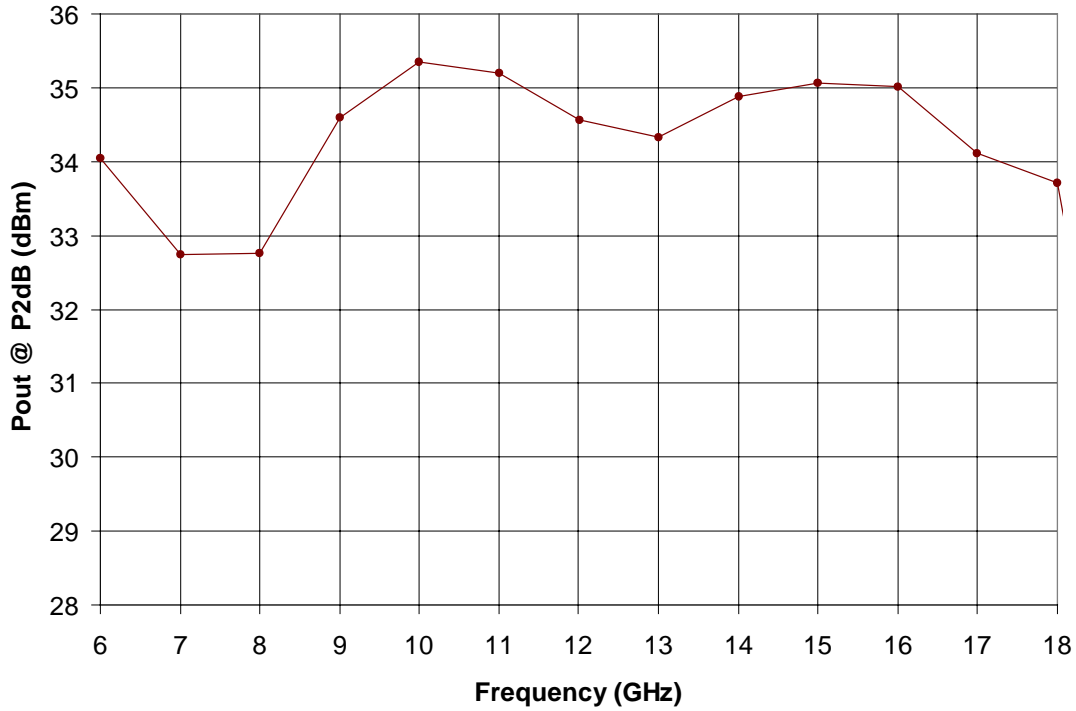
Parameter	Test Conditions	T_{CH} (°C)	$R_{\theta JC}$ (°C/W)	T_M (HRS)
$R_{\theta JC}$ Thermal Resistance (channel to backside of carrier)	$V_d = 8\text{V}$ $I_D = 2.4\text{A}$ $P_{diss} = 19.2\text{W}$	144.56	3.88	1.6 E+6

Note: Assumes eutectic attach using 1.5 mil 80/20 AuSn mounted to a 20 mil CuMo Carrier at 70°C baseplate temperature. Worst case condition with no RF applied, 100% of DC power is dissipated.

* This information is a result of a thermal model analysis based on the entire two-channel device.

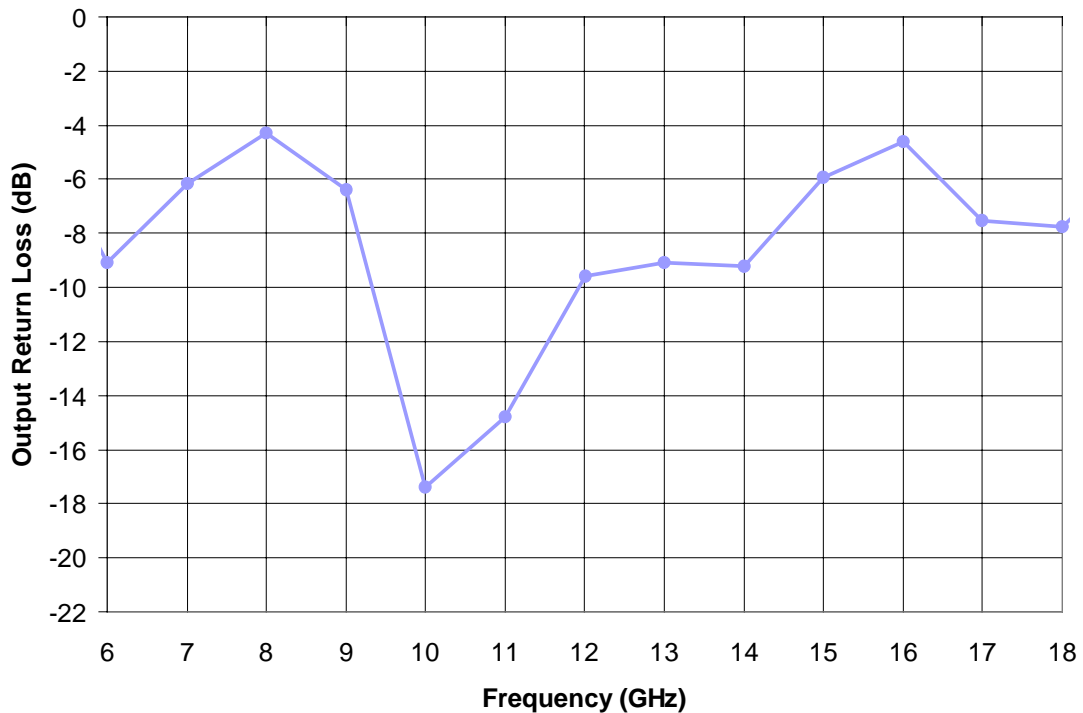
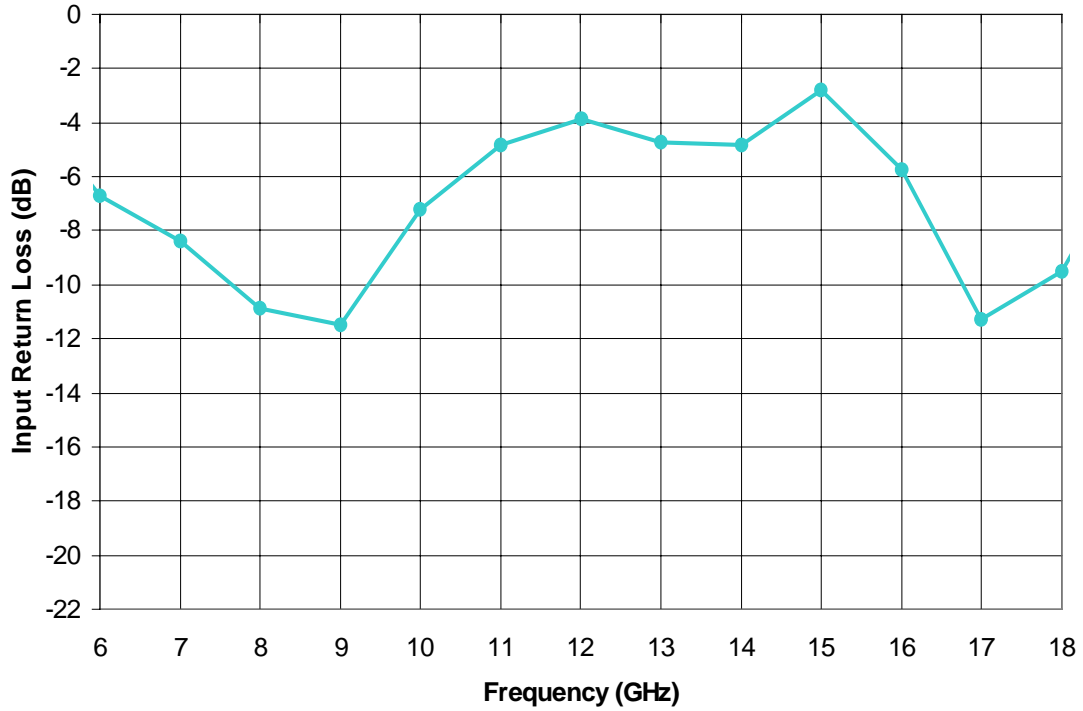
**Data Based on the 50th Percentile On-Wafer RF
Probe Test Results, Sample Size = 3370 Devices**

Bias Conditions: $V_d = 8\text{ V}$, $I_d = 1.2\text{ A}$



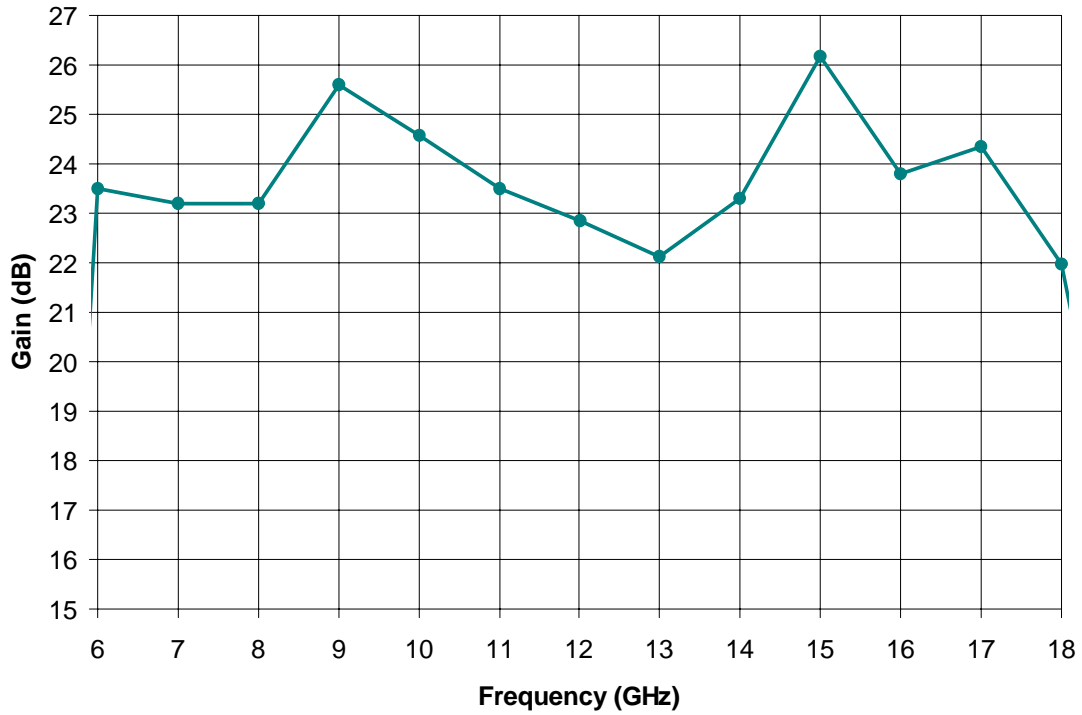
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Bias Conditions: $V_d = 8\text{ V}$, $I_d = 1.2\text{ A}$

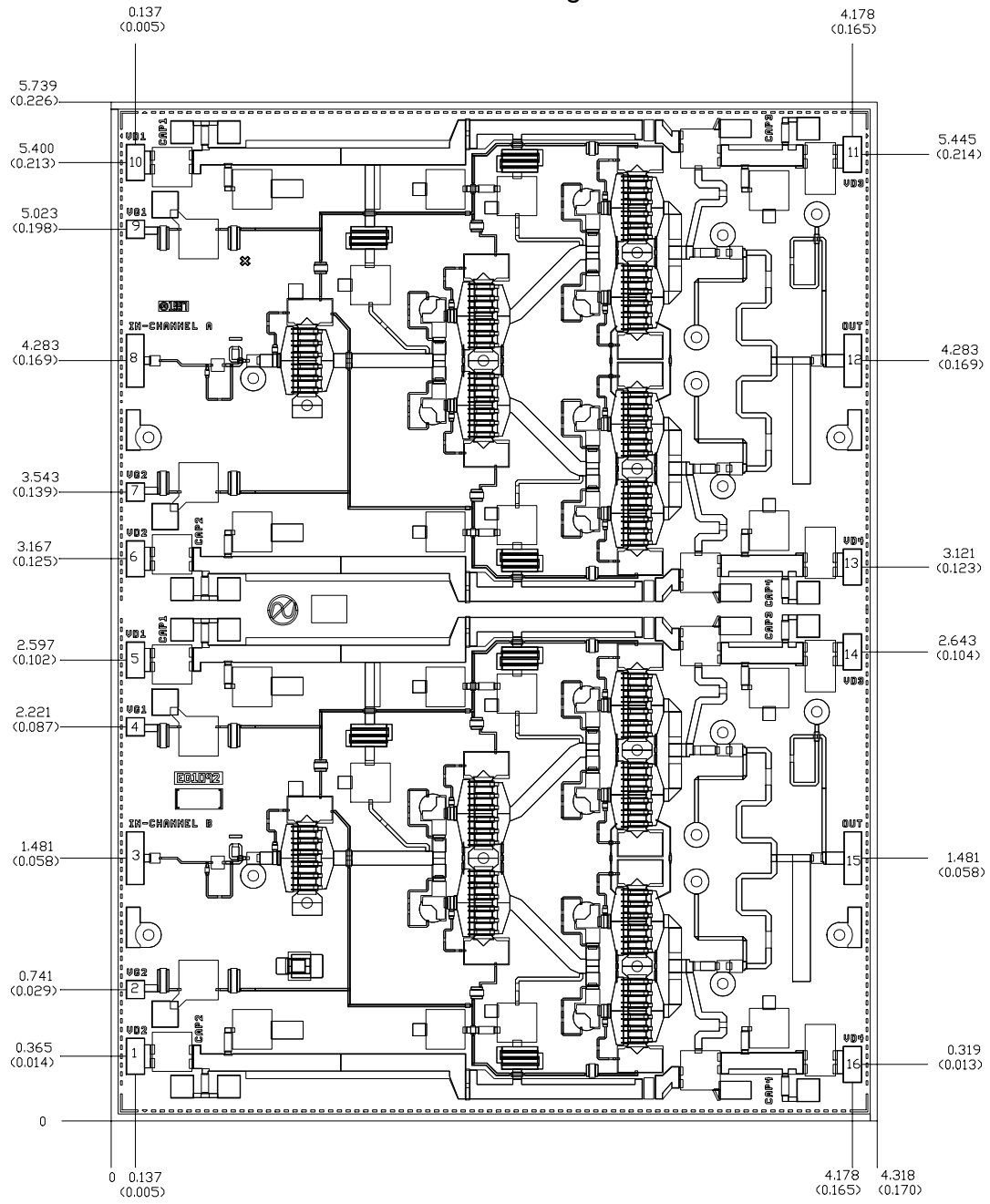


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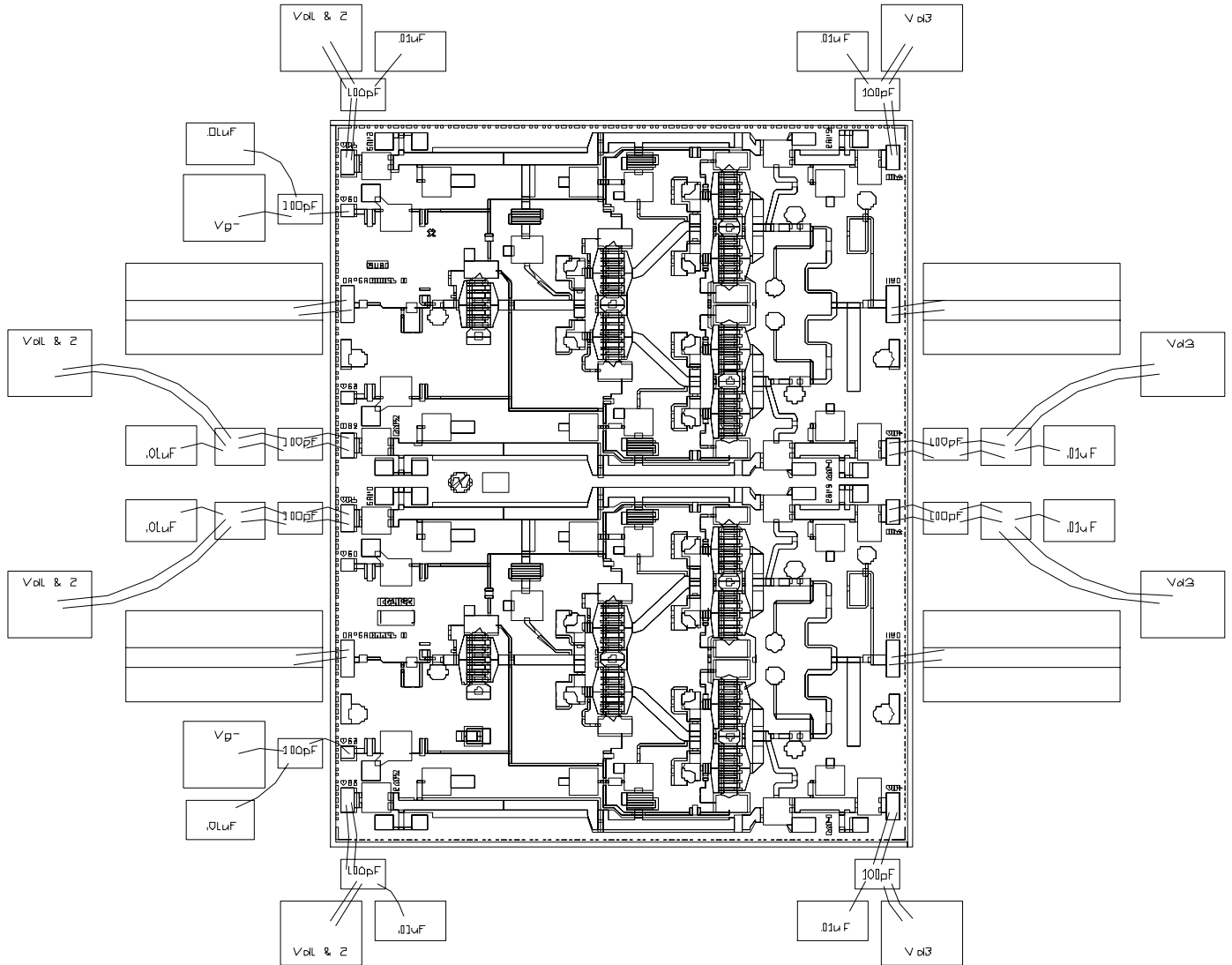
Mechanical Drawing



Units: millimeters (inches)
 Thickness: 0.1016 (0.004) (reference only)
 Chip edge to bond pad dimensions are shown to center of Bond pads.
 Chip size tolerance: +/- 0.0508 (0.002)

Bond Pad #1,5,6,10 (Vd1&Vd2)	0.100 x 0.200	(0.004 x 0.008)
Bond Pad #11,13,14,16 (Vd3)	0.100 x 0.200	(0.004 x 0.008)
Bond Pad #2,4,7,9 (Vg)	0.100 x 0.100	(0.004 x 0.004)
Bond Pad #3,8 (RF Input)	0.100 x 0.300	(0.004 x 0.012)
Bond Pad #12,15 (RF Output)	0.100 x 0.300	(0.004 x 0.012)

Chip Assembly and Bonding Diagram



Note: All Vd's may be connected external to the MMIC.

GaAs MMIC devices are susceptible to damage from Electrostatic Discharge. Proper precautions should be observed during handling, assembly and test.

Assembly Process Notes

Reflow process assembly notes:

- Use AuSn (80/20) solder with limited exposure to temperatures at or above 300°C.
- An alloy station or conveyor furnace with reducing atmosphere should be used.
- No fluxes should be utilized.
- Coefficient of thermal expansion matching is critical for long-term reliability.
- Devices must be stored in a dry nitrogen atmosphere.

Component placement and adhesive attachment assembly notes:

- Vacuum pencils and/or vacuum collets are the preferred method of pick up.
- Air bridges must be avoided during placement.
- The force impact is critical during auto placement.
- Organic attachment can be used in low-power applications.
- Curing should be done in a convection oven; proper exhaust is a safety concern.
- Microwave or radiant curing should not be used because of differential heating.
- Coefficient of thermal expansion matching is critical.

Interconnect process assembly notes:

- Thermosonic ball bonding is the preferred interconnect technique.
- Force, time, and ultrasonics are critical parameters.
- Aluminum wire should not be used.
- Discrete FET devices with small pad sizes should be bonded with 0.0007-inch wire.
- Maximum stage temperature is 200°C.

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